

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	172	stainless steel with nickel with iron and (electro\$1deposit\$8 or electrophore\$3 or electro\$1form\$3 or electro\$1osmosis) same nickel same steel	US-PGPUB; USPAT	ADJ	ON	2008/05/30 15:04
L2	11	stainless steel with nickel near iron near2 alloy and (electro\$1deposit\$8 or electrophore\$3 or electro\$1form\$3 or electro\$1osmosis) same nickel same steel	US-PGPUB; USPAT	ADJ	ON	2008/05/30 15:09
L4	5936	invar	US-PGPUB; USPAT	ADJ	ON	2008/05/30 15:15
L5	84	invar with nickel near iron same mask	US-PGPUB; USPAT	ADJ	ON	2008/05/30 15:16
L6	0	5 and (electro\$1luminescen or light (emitt\$8 or emiss\$8) (device or diode or display) or OLED or PLED)	US-PGPUB; USPAT	ADJ	ON	2008/05/30 15:22
L7	8	(electro\$1luminescen or light (emitt\$8 or emiss\$8) (device or diode or display) or OLED or PLED) and nickel same (electro\$1deposit\$8 or electrophore\$3 or electro\$1form\$3 or electro\$1osmosis) same mask and mask with (vapor deposit\$8 or CVD or PVD or sputter\$3 or vacuum\$1vapor\$8)	US-PGPUB; USPAT	ADJ	ON	2008/05/30 15:25

L8	7	(electro\$1luminescen or light (emitt\$8 or emiss \$8) (device or diode or display) or OLED or PLED) and nickel same (electro\$1deposit\$8 or electrophore\$3 or electro \$1form\$3 or electro \$1osmosis) and mask with (vapor deposit\$8 or CVD or PVD or sputter\$3 or vacuum \$1vapor\$8) same nickel	US-PGPUB; USPAT	ADJ	ON	2008/05/30 15:30
L9	154	(electro\$1luminescen or light (emitt\$8 or emiss \$8) (device or diode or display) or OLED or PLED) and mask with (vapor deposit\$8 or CVD or PVD or sputter\$3 or vacuum \$1vapor\$8) same nickel	US-PGPUB; USPAT	ADJ	ON	2008/05/30 15:31
L11	19	nickel same (electro \$1deposit\$8 or electrophore\$3 or electro \$1form\$3 or electro \$1osmosis) and mask with (vapor deposit\$8 or CVD or PVD or sputter\$3 or vacuum \$1vapor\$8) same nickel	US-PGPUB; USPAT	ADJ	ON	2008/05/30 15:49
L13	1508	(electro\$1luminescen or light (emitt\$8 or emiss \$8) (device or diode or display) or OLED or PLED) and pixel near10 (mu or micron or micrometer)	US-PGPUB; USPAT	ADJ	ON	2008/05/30 16:40
L14	1	("5991073").PN.	US-PGPUB; USPAT	OR	OFF	2008/05/30 16:53
S1	611	118/720-721.ccls.	US-PGPUB; USPAT	ADJ	ON	2008/05/28 17:29
S2	1805	427/282.ccls.	US-PGPUB; USPAT	ADJ	ON	2008/05/28 17:29
S3	407	S1 or S2	US-PGPUB	ADJ	ON	2008/05/28 17:29
S4	1937	S1 or S2	USPAT	ADJ	ON	2008/05/28 17:30
S5	611	118/720-721.ccls.	US-PGPUB; USPAT	ADJ	ON	2008/05/29 09:55

S6	1805	427/282.ccls.	US-PGPUB; USPAT	ADJ	ON	2008/05/29 09:55
S7	114	(S5 or S6) and (hole or aperture) same (slant or funnel or angle or tilt)	US-PGPUB; USPAT	ADJ	ON	2008/05/29 09:55
S8	73	(S5 or S6) and (hole or aperture) with (slant or funnel or angle or tilt)	US-PGPUB; USPAT	ADJ	ON	2008/05/29 09:56
S9	1	("20040135498").PN.	US-PGPUB; USPAT	OR	OFF	2008/05/29 10:06
S10	9	(S5 or S6) and (multi \$1layer or (multiple or plurality) layer) near mask	US-PGPUB; USPAT	ADJ	ON	2008/05/29 10:47
S11	62	(S5 or S6) and (multi \$1layer or (multiple or plurality) (layer or material or composition)) with mask	US-PGPUB; USPAT	ADJ	ON	2008/05/29 10:49
S12	1	"6890385"	US-PGPUB; USPAT	ADJ	ON	2008/05/29 11:10
S13	8	("20020062785" "20030101932" "20030150384" "20030221614" "20040003775" "20040020435" "4915057" "6475287"). PN. OR ("6890385"). URPN.	US-PGPUB; USPAT; USOCR	ADJ	ON	2008/05/29 11:22
S14	2	jp-2003231964-\$.did.	JPO; DERWENT	ADJ	ON	2008/05/29 11:29
S15	2	jp-57026163-\$.did.	JPO; DERWENT	ADJ	ON	2008/05/29 11:31
S16	18	("20030150384" "20040003775" "20040020435" "3226255" "3713922" "4256532" "4335161" "4417946" "4715940" "4746548" "5234781" "5326426" "5669972" "6589382" "6592670" "6878209" "6890385" "6916582").PN.	US-PGPUB; USPAT	ADJ	ON	2008/05/29 11:39
S17	55687	"204".clas.	US-PGPUB; USPAT	ADJ	ON	2008/05/29 14:16
S18	93	S17 and 427/282.ccls.	US-PGPUB; USPAT	ADJ	ON	2008/05/29 14:16

S19	140	S17 and 118/720-721. ccls.	US-PGPUB; USPAT	ADJ	ON	2008/05/29 14:17
S20	6598	204/450-553 ccls.	US-PGPUB; USPAT	ADJ	ON	2008/05/29 14:26
S21	8	S20 and 427/282 ccls.	US-PGPUB; USPAT	ADJ	ON	2008/05/29 14:26
S22	0	S20 and 118/720-721. ccls.	US-PGPUB; USPAT	ADJ	ON	2008/05/29 14:26
S23	38	S20 and mask with (vapor deposit\$8 or CVD or PVD or PECVD or sputter\$3 or vaccum near \$1vapor\$8)	US-PGPUB; USPAT	ADJ	ON	2008/05/29 14:29
S24	159	mask with (vapor deposit \$8 or CVD or PVD or PECVD or sputter\$3 or vaccum near \$1vapor\$8) same (electro\$1deposit \$8 or electrophore\$3 or electro\$1form\$3 or electro\$1osmosis)	US-PGPUB; USPAT	ADJ	ON	2008/05/29 15:16
S25	2	jp-10305670-\$ did.	JPO; DERWENT	ADJ	ON	2008/05/29 15:21
S26	15	118/720-721.ccls. and (electro\$1deposit\$8 or electrophore\$3 or electro \$1form\$3 or electro \$1osmosis)	US-PGPUB; USPAT	ADJ	ON	2008/05/29 17:02
S27	37	mask and (vapor deposit \$8 or CVD or PVD or PECVD or sputter\$3 or vaccum near \$1vapor\$8) and (electro\$1deposit\$8 or electrophore\$3 or electro\$1form\$3 or electro\$1osmosis)	EPO; JPO	ADJ	ON	2008/05/29 17:12
S28	2	jp-10228114-\$ did.	JPO; DERWENT	ADJ	ON	2008/05/29 17:36
S29	46	(shadow or metal) mask and (electro\$1deposit\$8 or electrophore\$3 or electro\$1form\$3 or electro\$1osmosis)	EPO; JPO	ADJ	ON	2008/05/30 09:01
S30	2	jp-2006152396-\$ did.	JPO; DERWENT	ADJ	ON	2008/05/30 09:08
S31	2	jp-2003183811-\$ did.	JPO; DERWENT	ADJ	ON	2008/05/30 09:12

S32	181	(shadow or metal) mask same (electro\$1deposit \$8 or electrophore\$3 or electro\$1form\$3 or electro\$1osmosis)	US-PGPUB; USPAT	ADJ	ON	2008/05/30 09:16
S33	71	(shadow or metal) mask same (electro\$1deposit \$8 or electrophore\$3 or electro\$1form\$3 or electro\$1osmosis) same etch\$3	US-PGPUB; USPAT	ADJ	ON	2008/05/30 09:21
S34	3	jp-56059433-\$\$.did. or jp-57060640-\$\$.did.	JPO; DERWENT	ADJ	ON	2008/05/30 10:16
S35	1	("3,574,013").PN.	US-PGPUB; USPAT	OR	OFF	2008/05/30 10:42
S36	9	("20010001050" "6136622" "6165543" "6294892").PN. OR ("6417034").URPN.	US-PGPUB; USPAT; USOCR	ADJ	ON	2008/05/30 11:30
S37	1	("20030087471").PN.	US-PGPUB; USPAT	OR	OFF	2008/05/30 11:36
S38	227	electro\$1luminescen\$2 same (light (emitt\$8 or emiss\$8) (device or display or diode)) and hole (transfer\$8 or transport\$8) same hole inject\$8 same electron (transfer\$8 or transport \$8) same electron inject \$8 and (vapor deposit\$8 or CVD or PVD or PECVD or vaccum near \$1vapor \$8) with mask and (thin film transistor or TFT)	US-PGPUB; USPAT	ADJ	ON	2008/05/30 13:28

5/30/2008 4:55:05 PM

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